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Characterization of residual strain in seed-cast grown Si シードキャストシリコンインゴット中の残留歪の評価

NIMS¹, Tsukuba Univ.², Kyoto Inst. Techn.³, Kyushu Univ.⁴ [°]Karolin Jiptner^{1,2}, Masayuki Fukuzawa³, Yoshiji Miyamura¹, Hirofumi Harada¹, Koichi Kakimoto⁴, Takashi Sekiguchi^{1,2} 物材機構¹, 筑波大², 京都工繊大³, 九大⁴ [°]イプトナー・カロリン^{1,2}, 福澤理行³, 宮村佳児¹, 原田博文¹, 柿本浩一⁴, 関口隆史^{1,2}

E-mail: JIPTNER.Karolin@nims.go.jp

The seed-cast method has the big advantage of obtaining mono-Si ingots in an uncomplicated growth process. However, thermal stresses and the crucible constraint lead to high residual strain in the grown ingots, which can cause breakage during the handling and wafer fabrication process. It is of uttermost importance to analyze this residual strain and to find ways of eliminating and/or reducing stress during the crystal growth. In this study, the residual strain in seed-cast grown Si ingots was analyzed by SIRP^[1,2].

To understand in which process steps residual strain accumulates, several Si ingots were grown in a laboratory scale furnace (\emptyset 10cm) using different cooling conditions after completion of the solidification. Crystal 1 was cooled at 12° C/min throughout the complete temperature range, Crystal 2 was cooled first at 12° C/min and later the cooling rate was lowered to 5° C/min below 900° C, and Crystal 3 was first slowly cooled with 5° C/min, which was changed to 12° C/min cooling below 900° C. The SIRP images of the crystals are shown in Fig. 1. It was found that the changes in cooling gradients greatly influenced the amount of residual strain. In comparison to Crystal 1, Crystal 2 shows a reduction in residual strain by over 30% [3]. In Crystal 3 the reduction is more than 70%. This result suggests that thermal stresses in the high temperature region greatly influence the amount of residual strain.



(a) Crystal 1 (fast \rightarrow fast)





(b) Crystal 2 (fast \rightarrow slow) (c) Crystal 3 (slow \rightarrow fast)

Fig. 1: SIRP images of the grown crystals

Reference:

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